

01-09-02

Docket No. 6333/TCG/TSM/LPCVD/LE

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
 Assistant Commissioner for Patents
 Washington, D.C. 20231

Re: Inventor(s): Janardhanan Anand Subramony, Yoshitaka Yokota, Ramaseshan Suryanarayanan Iyer,
 Lee Luo, Aihua Chen

Title: METHODS FOR SILICON OXIDE AND OXYNITRIDE DEPOSITION USING SINGLE WAFER LOW PRESSURE
 CVD

Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 35 pages.
- ☒ Drawings totaling 15 pages, Formal ☒ Informal.
- ☒ Unsigned Declaration and Power of Attorney.
- ☐ Assignment of the invention to Applied Materials, Inc.
- ☒ Information Disclosure Statement (IDS)/PTO-1449 with copies of IDS citations.
- ☒ Check No. 47170 in the amount of \$1370.00

FEE CALCULATION

Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	27	- 20 =	7	X \$18.00	126.00
Independent Claims	9	- 3 =	6	X \$84.00	504.00
Basic Filing Fee				\$740.00	\$740.00
TOTAL FEES					\$1370.00

☐ The Commissioner is hereby authorized to charge \$() to Deposit Account No. 50-1074.

☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 02-2666. A duplicate copy of this transmittal is enclosed.

☒ Please address all future correspondence to:

PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O.BOX 450A
Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Box Patent Application, Assistant Commissioner for Patents, Washington, D.C. 20231.

Express Mail Receipt No. EL867648876US

Date of Deposit December 28, 2001

Signature Michelle Beg

Respectfully submitted,

Michael A. Bernadicou
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